

# In-Situ laser (TDLS) gas analyzer

PROCESS & EMISSIONS MONITORING SYSTEMS



- $\checkmark$  No sampling system needed
- ✓ No gas temperature influence
- ✓ Gas matrix interference free
- ✓ Calibration free measurement
- ✓ High precision gas concentration measurement and fast response time
- New Embedded ClearPath functionality

#### 💡 CLEARPATH

Interference of relative humidity,  $O_2$  or  $CO_2$  is removed in purging areas.

Operator's benefits:

- No need for N<sub>2</sub> or dry air purge
- High accuracy of O<sub>2</sub> measurement
- High accuracy of H<sub>2</sub>O measurement
- High accuracy of CO<sub>2</sub> measurement



Embedded web server

#### **KEY FEATURES**

- Highly sensitive and selective measurement
- High signal-to-noise ratio
- No measurement drift
- Response time 1 s
- Large dynamic range from ppm to %
- Real-time communication between Transmitter (Tx) and Receiver (Rx)
- Robust, ready for Ex Zone II (certification to come)

#### A WIDE RANGE OF APPLICATIONS FOR CEMS AND PROCESS

- Ammonia slip control (DeNox)
- Process and combustion control
- HF emission control in aluminum plant
- HCI/SO<sub>2</sub> abatement control
- Ethylene cracking furnace control
- HCl level in semiconductor production
- Ammonia concentration control in pet food, fertilizer plants, etc.

#### CUSTOMER BENEFITS

- > Low maintenance and cost of ownership
- > No need for  $N_2$  or dry air purge: Oil & dust free air instrument is enough
- > Process optimization leading to reduction of operating costs

5000XI

## In-Situ laser (TDLS) gas analyzer **LAS 5000XD**



### **TECHNICAL SPECIFICATIONS**

Concentration ranges:		
$\begin{array}{c} {\sf NH}_3 + {\sf H}_2{\sf O} \\ {\sf HF} \\ {\sf CO} \; {\sf ppm} + {\sf H}_2{\sf O} \\ {\sf CO}\% + {\sf H}_2{\sf O} \\ {\sf CO}\% + {\sf CO}_2 \\ {\sf CO}_2 + {\sf H}_2{\sf O} \\ {\sf O}_2 \\ {\sf HCI} + {\sf H}_2{\sf O}^* \\ {\sf Other \ gases} \end{array}$	0-10 ppm / 0-5000 ppm + 0-5% / 0-50% 0-3 ppm / 0-500 ppm 0-50 ppm / 0-1% + 0-10% / 0-50% 0-1% / 0-100% + 0-1% / 0-50% 0-1% / 0-100% + 0-1% / 0-50% 0-1% / 0-100% + 0-10% / 0-50% (*gas temperature must be above 150°C). Available upon request: $CH_4$ , $H_2S$ , $H_2$ , NO	
Technology	<ul> <li>ADLAS (Advanced Detection Laser Absorption Spectroscopy)</li> <li>Optimized Opto-Mechanical Design</li> <li>High Speed Low-Drift Electronics</li> <li>Independent Spectroscopy Technique</li> </ul>	
Lower Detection Limit	< 1% of FS	
Response Time (0-90%) - Short	1 s	
Lack of fit/Linearity	$\leq \pm 1\%$	
Flue Gas Temperature (°C max) NH <sub>3</sub> + H <sub>2</sub> O / HCl + H <sub>2</sub> O / HF CO + H <sub>2</sub> O / O <sub>2</sub> / CO + CO <sub>2</sub>	+400 °C (Depends on the concentration range) +1200 °C (Depends on the concentration range)	
Flue Gas Pressure	2 bars max (absolute)	
Display on Tx	4 x 20 LCD	
Communication	Modbus RTU (RS485) / Ethernet (RJ45) - Web server	
Power supply type	+ 24 V DC, ripple and noise 50 mV	
Power consumption	15 W (warm-up), < 15 W in standard use	
Recommended T° (ambient)	-20 °C to +55 °C	
IP index Tx & Rx enclosures	IP65	
Flange specification requirement on stack	DN50 PN16, 2" - 150 lbs, Class 150	
Flange material	SS 316 L	
Air consumption (main purge - necessary)	5-50 L/min (to adjust according to site conditions) (dry and oil free, ISO 8573.1 Class 2-3)	
Air consumption (secondary purge - recommended)	2-3 L/min (dry and oil free, ISO 8573.1 Class 2-3)	
Stack diameter compatibility	From 0.5 to 20 m	
Note The technical presidentians are defined in the following conditions: Casternary two = 25 % / cas		

Note - The technical specifications are defined in the following conditions: Gas temperature = 25 °C / gas pressure = 1013 mbar / pathlength = 100 cm / ambient temperature = 25 °C

### OPTIONS

Junction Box :	Analog I/O (2 x 4-20 mA/2 x 4-20 mA) - Digital Output (2 relays)
Thermal Shield	Thickness: 20 mm (100°C <tp<300°c) (300°c<tp<600°c)="" 40="" ;="" ;<br="" mm="">60 mm (Tp above 600°C).</tp<300°c)>
Audit Cell	
Inline Cell	

Alignment Tool

Weather protection covers



ENVEA (Headquarters) 111 Bd Robespierre - CS 80004 78300 Poissy / Cedex 4 - FRANCE ☎ +33(0) 1 39 22 38 00 ☑ info@envea.global



